

Field of Experience	Related Methodology or Tool	Summary
SF6	NM0271	<p>The proposed new methodology NM0271, which is under consideration of the Meth Panel, is applicable to project activities related to abatement of SF6 used in etch process of LCD manufacturing industry.</p> <p>Expert input is required on issues regarding SF6 for different type and/or quality of LCD product manufactured. This input will be used in determining emission reductions due to abatement efforts in existing etch processes.</p>